



Accordance OCR Recognition Macro Automatic Control Solutions

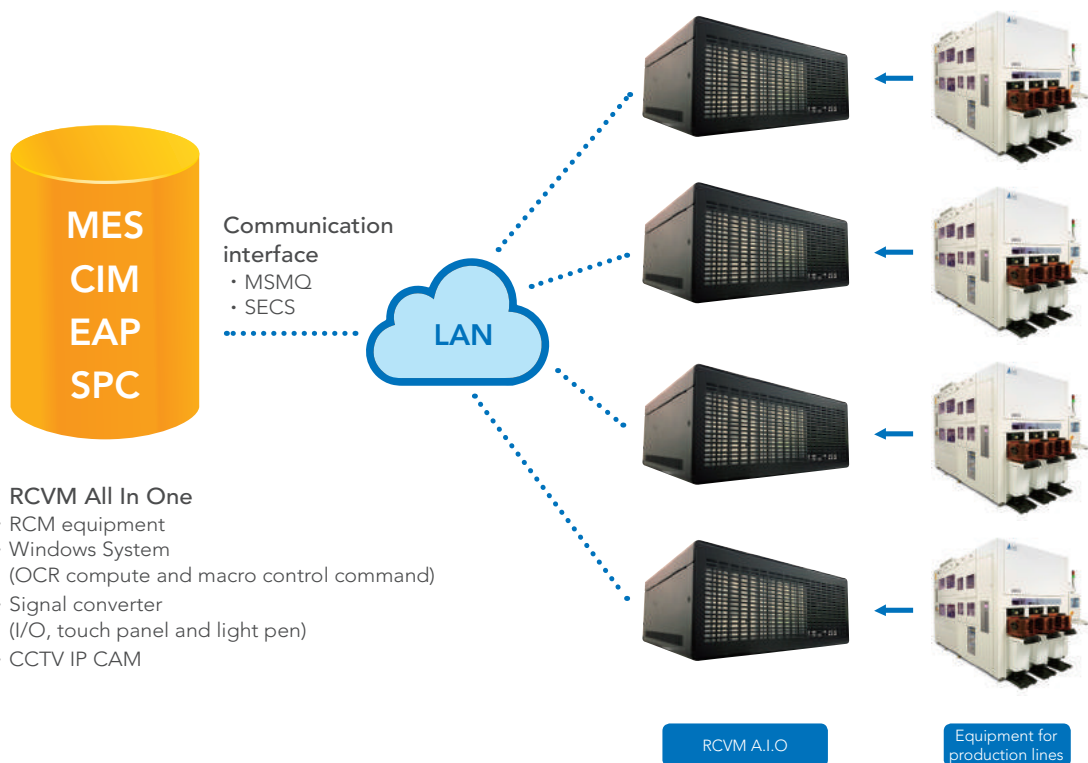
Advance Remote Control

Application:

Clean room environment, semiconductor wafer
OEM, semiconductor package test, panel plants,
and electronic plants

Current challenges: Machine data collection, common alarm clearance
Mistakes from manual operation, non-SECS and no
communication
Interface machines need to be operated manually

OCR Recognition Macro Automatic Control System The framework diagram



The benefits of introducing ARC System

Reduce expensive cost for upgrading/implementing SECS/GEM communication,
Non-automated equipment upgraded to semi-automated equipment,
Eliminate human errors in inputting recipes,
Collect data and information (Auto Data Collection),
Immediate response to machine alarms.